


APPLICATION DATA SHEET

Electronic Version v14

Stylesheet Version v14.0

Title of Invention	Method and System for Scatter Correction During Bi-Plane Imaging with Simultaneous Exposure		
Application Type : regular, utility			
Attorney Docket Number : GEMS 0169 PA			
Correspondence address:			
Customer Number:		027256	
Inventors Information:			
<u>Inventor 1:</u>			
Applicant Authority Type:	Inventor		
Citizenship:	US		
Name prefix:	Mr.		
Given Name:	John		
Middle Name:	Robert		
Family Name:	Lamberty		
Residence:			
City of Residence:	Oconomowoc		
State of Residence:	WI		
Country of Residence:	US		
Address-1 of Mailing Address:	429 So. Concord Rd.		
Address-2 of Mailing Address:			
City of Mailing Address:	Oconomowoc		
State of Mailing Address:	WI		
Postal Code of Mailing Address:	53066		
Country of Mailing Address:	US		
Phone:			
Fax:			
E-mail:			
<u>Inventor 2:</u>			
Applicant Authority Type:	Inventor		
Citizenship:	US		
Name prefix:	Mr.		

Given Name: James
Middle Name: G.
Family Name: Morrow
Residence:
City of Residence: Wauwatosa
State of Residence: WI
Country of Residence: US
Address-1 of Mailing Address: 627 N. 78th Street
Address-2 of Mailing Address:
City of Mailing Address: Wauwatosa
State of Mailing Address: WI
Postal Code of Mailing Address: 53213
Country of Mailing Address: US
Phone:
Fax:
E-mail:

Publication Information:
Suggested Figure for Publication - Figure 1
Suggested Classification -
Suggested Technology Center -
Total Number of Drawing Sheets - 5

Assignee 1:

Organization Name: GE Medical Systems Global Technology Company, LLC
Address-1 of Mailing Address: 3000 North Grandview Blvd.
Address-2 of Mailing Address:
City of Mailing Address: Waukesha
State of Mailing Address: WI
Postal Code of Mailing Address: 53188-1615
Country of Mailing Address: US
Phone:
Fax:
E-mail: